

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Emir Gurer, et al.

Application No.: 09/874,073

Filed: June 4, 2001

Attorney Docket No.: 006601.P036C

For: PLASMA DEPOSITION OF SPIN
CHUCKS TO REDUCE
CONTAMINATION OF SILICON
WAFERS



Examiner: Ram N. Kackar

Art Unit: 1763

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION

UNDER 37 CFR 1.116

Sir:

In response to the Final Office Action mailed June 16, 2003, applicants respectfully request that the following amendment and remarks be considered.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450 on October 29, 2003.

Christine Donahue
(Typed or printed name of person mailing correspondence)

(Signature of person mailing correspondence)